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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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|------------------------|--|------------------|-------------------|
| In Re: | Detlef Michelsson | Confirmation No: | 5672 |
| Serial No: | 10/772,510 | Group: | 2609 |
| Filed: | February 5, 2004 | Examiner: | Fujita, Katrina R |
| For: | Method and Apparatus for Examining Semiconductor Wafers in a Context of DIE/SAW Design | | |
| Customer No.: | 29127 | | |
| Attorney Docket No. | 21295.74US (H5742US) | | |

AMENDMENT AND REPLY

VIA FACSIMILE: 571-273-8300
Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

Sir:

In response to the pending Office Action, mailed February 5, 2007, please amend the above-captioned application as follows:

- amendments to the specification are set forth in section a);
- amendments to the claims are reflected in the listing of claims in section b);
- and finally, reconsideration is requested in view of the remarks set forth in section c).